

**CLEAN VERSION OF REWRITTEN OR ADDED CLAIMS
PURSUANT TO 37 CFR § 1.21 (c)(1)(i)**

Please cancel Claims 2, 4, 7 and 9.

Please amend the following claims.

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1. (Amended) A device comprising a microdroplet transport channel etched in substrate, said substrate selected from the group consisting of silicon, quartz and glass, said channel comprising one or more hydrophobic regions, wherein said device further comprises a gas-intake pathway in fluidic communication with said microdroplet channel and wherein one of said hydrophobic regions is positioned in said channel between said gas-intake pathway and said gas vent. NAB

6. (Amended) A device comprising a microdroplet transport channel, said channel comprising i) first and second ends, and ii) a hydrophobic region disposed within said channel between said first and second ends, wherein said device further comprises a gas-intake pathway positioned internal to said first end of said channel, said gas-intake pathway in fluidic communication with said microdroplet channel, and further wherein said hydrophobic region is positioned in said channel between said gas-intake pathway and said gas vent. NAB

10. The device of Claim 6, wherein said first end of said channel comprises an inlet port for the introduction of liquid.